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Development of CMOS-MEMS Sensors and Devices

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Message from the Guest Editors

CMOS-MEMS represents a cutting-edge technology where monolithic or hybrid MEMS are seamlessly integrated with CMOS circuitry. CMOS-MEMS encompasses both the devices and the microfabrication processes essential for their creation. Within this realm, MEMS transducers excel at sensing and controlling physical, optical, or chemical properties, while ICs play a pivotal role in managing the signals generated by these transducers. Furthermore, a notable trend involves the creation of multi-functional devices concurrently on the same CMOS chip, serving as versatile sensing nodes for specific applications. This Special Issue aims to collate research papers and review articles that delve into three primary areas: (1) innovations in the design, fabrication, control, and modeling of CMOS-MEMS devices employing diverse mechanisms; (2) the integration of multi-functional CMOS-MEMS devices as efficient information collection nodes; (3) the latest developments in the application of CMOS-MEMS devices across various sectors, including consumer electronics, optical communications, industrial settings, healthcare, agriculture, aerospace, and defense.

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Message from the Editor-in-Chief

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